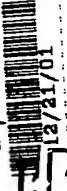


3578 U.S. PTO
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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10029080	12/21/2001	438		4765	

**APPLICANTS: Saka Nannaji; Nam Jamie; Oh Hilario;

**CONTINUING DATA VERIFIED:
This application is a CIP of 09/628,471 07/31/2000 PAT 6,476,921
and claims benefit of 60/258,931 12/29/2000

** FOREIGN APPLICATIONS VERIFIED:
UNITED STATES OF AMERICA PCT/US01/24146 07/31/2001

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no
35 USC 119 conditions met ☐ yes ☐ no
Verified and Acknowledged Examiners's initials

ATTORNEY DOCKET NO

A-69174-1/MSS

TITLE : In-situ method and apparatus for end point detection in chemical mechanical polishing

U S DEPT OF COMM /PAT. & TM-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drwg.	Figs.Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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